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Facsimile Cover Sheet

DATE: December 16, 2003
FILE NO: AMAT/2592.C6/DSM/LOW K/JW
TO: Office of Initial Patent Examination
FAX NO: (703) 746-9195
PHONE NO:
COMPANY: USPTO
FROM: B. Todd Patterson / Penny Moses
PAGE(S) with cover: 4
ORIGINAL TO FOLLOW? YES NO

TITLE: Method of Decreasing the K Value in SiOC Layer Deposited by Chemical Vapor Deposition
U.S. SERIAL NO.: 10/632,179
FILING DATE: July 31, 2003
INVENTOR: Gaillard, et al.
EXAMINER: Unknown
GROUP ART UNIT: 2812
CONFIRMATION NO.: 9827

CONFIDENTIALITY NOTE

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**In re Application of:
Gaillard, et al.**

Serial No.: 10/632,179

Filed: July 31, 2003

Confirmation No.: 9827

For: Method of Decreasing the
K Value in SiOC Layer
Deposited by Chemical
Vapor Deposition

Commissioner for Patents
Office of Initial Patent Examination
Filing Receipt Corrections
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir,

Group Art Unit: 2812

Examiner: Unknown

**CERTIFICATE OF FACSIMILE
TRANSMISSION UNDER 37 CFR 1.8**

REQUEST FOR CORRECTION OF ERROR ON FILING RECEIPT

The Filing Receipt for the above-referenced application contains an error regarding the Domestic Priority Data.

Please insert the following Domestic Priority Data information:

a CIP of 09/553,461 04/19/2000 PAT 6,593,247

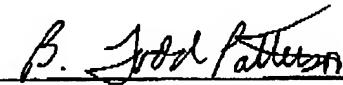
a CIP of 09/162,915 09/29/1998 PAT 6,287,990

a CIP of 09/185.555 11/04/1998 PAT 6,303,523

a CIP of 09/247,381 02/10/1999 PAT 6,348,725.

Attached is a copy of the Filing Receipt with the above change noted thereon.
Please correct this error or notify the applicants of the reasons for denying the request.

Respectfully submitted,


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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY.DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/632,179	07/31/2003	2812	✓750	✓AMAT/2592.C6/DSM/LOW K/JW	✓	✓20	✓3

CONFIRMATION NO. 9827

✓ Patent Counsel
 APPLIED MATERIALS, INC.
 P.O. Box 450-A
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FILING RECEIPT



NOV 11 2003

OC000000011158276

Date Mailed: 11/03/2003

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

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Assignment For Published Patent Application

✓ Applied Materials, Inc.;

Domestic Priority data as claimed by applicant

✓ This application is a CON of 09/679,843 10/05/2000 PAT 6,627,532
 ✓ which is a CIP of 09/465,233 12/16/1999 PAT 6,511,903
 ✓ which is a CON of 09/021,788 02/11/1998 PAT 6,054,379

* INSERT HERE *

Foreign Applications

✓ If Required, Foreign Filing License Granted: 10/28/2003

✓ Projected Publication Date: 02/12/2004

✓ Non-Publication Request: No